



RESPONSE UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 2125

00862.022239 (862.C2239)

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
SHIGEYUKI UZAWA, ET AL. )  
Application No.: 09/864,309 )  
Filed: May 25, 2001 )  
For: EXPOSURE APPARATUS, COATING/DEVELOPING )  
SYSTEM, DEVICE MANUFACTURING SYSTEM, )  
DEVICE MANUFACTURING METHOD, )  
SEMICONDUCTOR MANUFACTURING FACTORY, )  
AND EXPOSURE APPARATUS MAINTENANCE )  
METHOD )

: Examiner: Ryan A. Jarrett  
: Group Art Unit: 2125  
: Confirmation No.: 2803  
: March 22, 2005

Do not enter  
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BJ

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

Sir:

Introductory Comments

In response to the final Official Action dated December 22, 2004, please amend  
the above-identified application as follows, pursuant to 37 C.F.R. § 1.116: